

IN THE SPECIFICATION:

On page 1, before the heading BACKGROUND OF THE INVENTION, please add the following new paragraph.

-- CROSS-REFERENCE TO RELATED APPLICATIONS

This application claims priority from Japanese Patent Application No. 332541/2002 filed November 15, 2002. --

Also, please replace the abstract with the following.

-- ABSTRACT

A flow sensor and a flow rate measuring method are disclosed, in which an error caused by dust attached to the flow sensor is accurately corrected taking advantage of the fact that the output characteristic of the flow sensor representing the relation between the temperature measured by a temperature measuring unit and the flow rate of the fluid undergoes a change with the dust attached. The flow sensor includes a thin-film bridge unit formed on a substrate, a heater arranged on the bridge unit, and a temperature measuring unit arranged on the bridge unit. --